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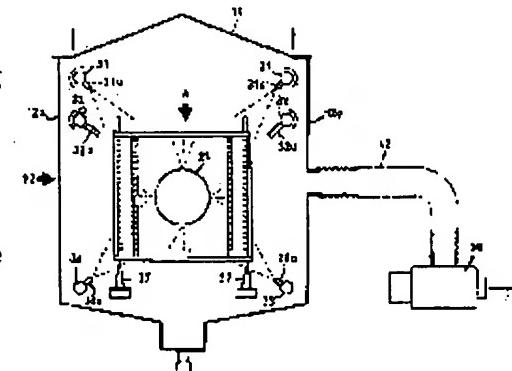
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## (54) WASHING METHOD FOR SUBSTRATE CASSETTE RACK

### (57) Abstract:

**PROBLEM TO BE SOLVED:** To provide a method for automatically and efficiently wash cassette racks for substrate, etc., within a washing casing.

**SOLUTION:** This washing method has a stage for housing and setting the cassette rack A of the substrates in the prescribed position in a washing casing 12 opened in part of at least its front surface wall, then washing the entire area in the lower part of the outer side of the cassette rack A with the waste liquid ejected out of nozzles 33a, a stage for washing the entire area exclusive of the rear surface of the cassette rack A with the waste liquid ejected out of nozzles 31a which are disposed above the right and left side of the cassette and oscillated in a vertical direction and a stage for washing the entire area of the inside surfaces of the cassette rack A with the waste liquid ejected out of the nozzles which are inserted from the front surface opening of the washing liquid casing 12 and move forward and backward while turning. After the entire area of the inside and outside surfaces of the cassette rack A is washed by the selective combination of the respective washing stage described above, air is blown to the entire area of the inside and outside surfaces of the cassette rack A to drain the residual waste liquid.



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